

**Electronic Patent Application Fee Transmittal**

<b>Application Number:</b>	09605293			
<b>Filing Date:</b>	28-Jun-2000			
<b>Title of Invention:</b>	METHOD FOR CONTROLLING THE MORPHOLOGY OF DEPOSITED SILICON ON A SILICON DIOXIDE SUBSTRATE AND SEMICONDUCTOR DEVICES INCORPORATING SUCH DEPOSITED SILICON			
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<b>Filer:</b>	Susan M. Luna/Beth Bane			
<b>Attorney Docket Number:</b>	MIO 0037 VA			
Filed as Large Entity				
<b>Utility under 35 USC 111(a) Filing Fees</b>				
<b>Description</b>	<b>Fee Code</b>	<b>Quantity</b>	<b>Amount</b>	<b>Sub-Total in USD(\$)</b>
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
Filing a brief in support of an appeal	1402	1	540	540
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				540